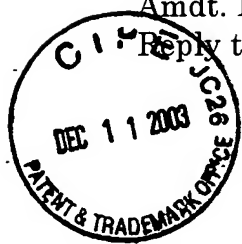


Appl. No. 10/008,958
Amdt. Dated December 8, 2003
Reply to Office Action of September 8, 2003

Attorney Docket No. 81790.0227
Customer No. 26021



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
Miki SASAKI, et al.
Serial No.: 10/008,958
Confirmation No.: 5427
Filed: December 5, 2001
For: SEMICONDUCTOR DEVICE
INCORPORATING A DICING
TECHNIQUE FOR WAFER
SEPARATION AND A METHOD FOR
MANUFACTURING THE SAME (As
Amended)

Art Unit: 2814
Examiner: Nathan W. Ha

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December 8, 2003

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Signature

12/08/03

Date

AMENDMENT UNDER 37 C.F.R. § 1.116

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action dated September 8, 2003, please amend
the above-referenced application as follows:

Amendments to the Claims are reflected in the Listing of Claims, which
begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.

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